Session TH1C

On-Wafer Measurements

Chairman:

H.M. Cronson
The MITRE Corporation

This session presents a wide variety of on-wafer measurement techniques showing the progress and broad interest in the important topic. The first three papers address non-linear measurements. The fourth paper treats vector corrected two-tone intermodulation measurements. Paper 5 describes an improved calibration technique for thin substrates. A new approach to 2D electro-optic probing is described in paper 6. In paper 7 a freely positionable photoconductive probe is described.

8:30 a.m.–10:00 a.m., Thursday, May 18, 1995
Room 12A,B,C